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On behalf of Argonne National Laboratory and the workshop organizing committee, we invite you to be an industrial exhibitor at the 18<sup>th</sup> International Workshop on ECR Ion Sources (ECRIS08) on September 15-18, 2008 at the Chicago History Museum in Chicago, Illinois, USA.

The workshop is an important forum for scientists and engineers working on ECR ion sources, with an anticipated attendance of 80-90 participants. Technologies used in these ion sources include components and systems for vacuum generation and analysis, beam transport and diagnostics equipment, high current and high voltage power supplies, isotopic materials, high performance ceramics, high field permanent magnets, normal and superconducting magnets, cryostat and cryocoolers, and microwave devices such as klystrons, traveling wave tubes, and gyrotrons.

The workshop program runs from 9 a.m. on Monday, September 15<sup>th</sup> until 3 p.m. on Thursday, September 18<sup>th</sup>, with exhibition days on Tuesday and Wednesday. Exhibitors will be located in the Chicago Room of the History Museum, adjacent to the session location and in the same area as the coffee breaks. The space will be available for set up on Monday at 1:30 p.m. with teardown to be completed by Thursday at 9 a.m. The fee for each exhibitor table, which is 6'x30" and includes two chairs and access to 115 V electrical power, is \$1000. The fee also includes a copy of the workshop program, inclusion of your company literature in the workshop bag, your company name in the workshop program, and a link to your company on the workshop website.

We are also offering an opportunity to further raise your company profile through sponsorship of workshop breaks.

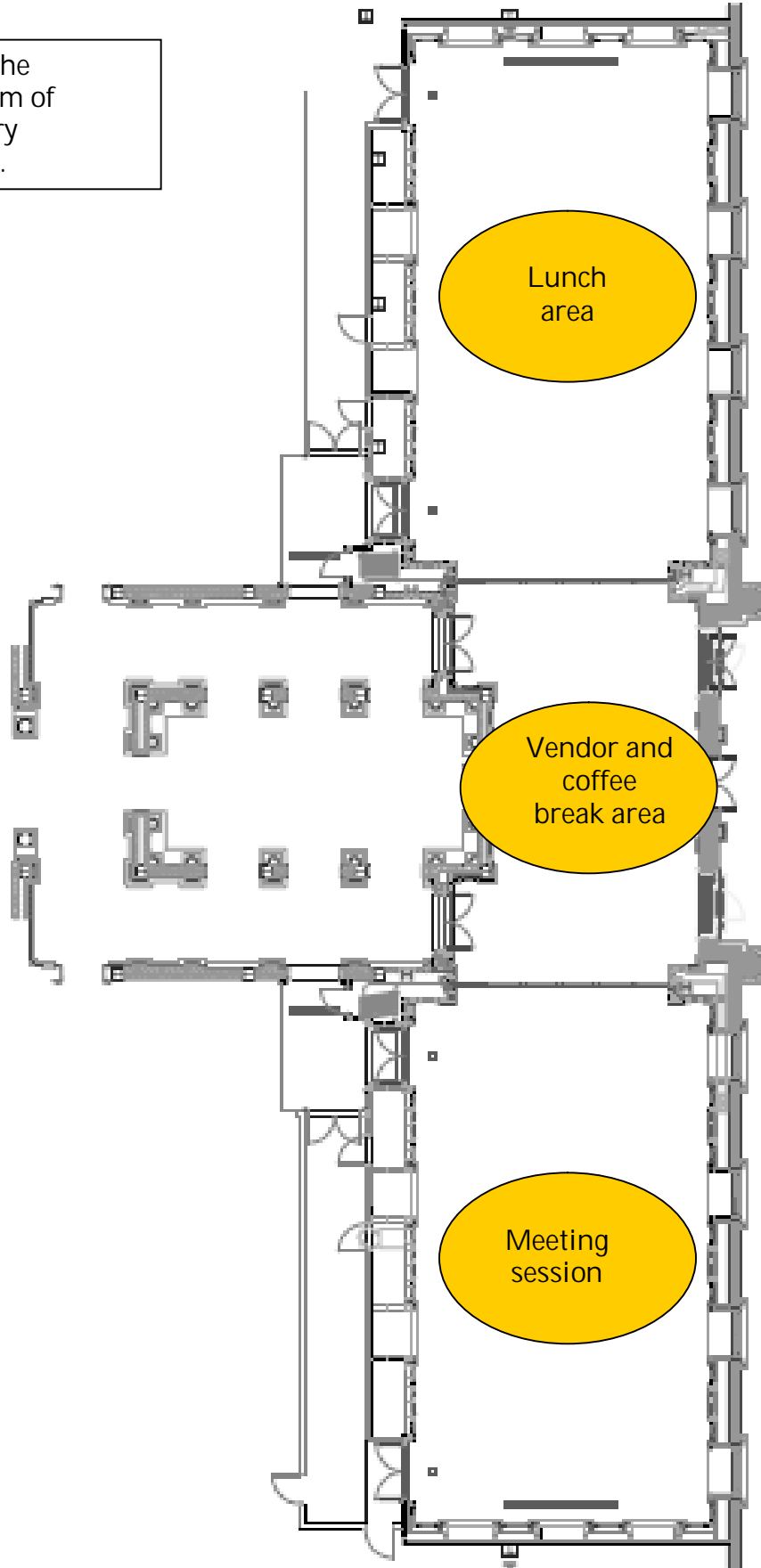
<b>Event</b>	<b>Description &amp; promotion</b>	<b>Pricing &amp; sponsors needed</b>	
Coffee break	Held at 10 a.m. and 3:30 p.m. daily Sign noting sponsorship	\$500	(6)

We encourage you to make use of this opportunity to meet with the ECR ion source community and exhibit your company's products. Please complete and return the vendor registration form with payment by July 14, 2008. Table and sponsorship registrations will be taken on a first come, first served basis. Also visit the workshop web site at [www.phy.anl.gov/ECRIS08](http://www.phy.anl.gov/ECRIS08) or contact me at [Vondrasek@anl.gov](mailto:Vondrasek@anl.gov) for further information. We look forward to seeing you in Chicago in 2008.

Sincerely,

Richard Vondrasek  
Co-Chairman, ECRIS08

Layout of the Chicago Room of the History Museum.



# DRAFT PROGRAM

Sunday, September 14, 2008	Monday, September 15, 2008	Tuesday, September 16, 2008	Wednesday, September 17, 2008	Thursday, September 18, 2008
	8:30-9:30 Opening Session	8:30-10:00 New Developments Status Reports I	8:30-10:00 New Concepts Next Generation ECRIS	8:30-10:00 Radioactive Ion Beams
	9:30-10:30 Superconducting ECRIS I	10:00-10:45 Coffee Break	10:00-10:45 Coffee Break	10:00-10:45 Coffee Break
	10:30-11:00 Coffee Break			
	11:00-12:30 Superconducting ECRIS II	10:45-12:30 New Developments Status Reports II	10:45-12:30 Charge Breeding	10:45-12:30 ECRIS Plasma Physics and Techniques
	12:30-14:00 Lunch	12:30-14:00 Lunch	12:30-21:30 Lunch Excursion Banquet	12:30-14:00 Lunch
	14:00-15:30 New Developments New Sources I	14:00-15:30 Applications and Diagnostics		14:00-15:00 Ion Beam Extraction Beam Transport
	15:30-17:30 Coffee Break Poster Session I	15:30-17:30 Coffee Break Poster Session II		15:00-15:30 Closing Remarks
				15:30-16:00 Coffee Break
18:00-22:00 Welcome Reception Registration		17:30-19:30 Vendor Sponsored Reception		16:00-20:00 Argonne Tour